

42.P17274



OIC to enter

BT  
4/20/06

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Fu, et al.

Serial No.: 10/672,357

Filed: September 25, 2003

For: PROCESS FOR LOW K  
DIELECTRIC PLASMA ETCHING WITH  
HIGH SELECTIVITY TO DEEP UV  
PHOTORESIST

Examiner: Binh X. Tran

Group Art Unit: 1765

Attorney Docket No.: 42.P17274

CERTIFICATE OF MAILING

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1.8(a)(1)(i)(ii)

Katherine Jennings

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Response Under 37 C.F.R. §1.116  
Expedited Procedure  
Technology Center 1700

AMENDMENT

Hon. Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

In response to the March 28, 2006 Final Office Action, please consider the following  
amendments and remarks:

**Amendments to the Claims begin on page 2.**

**Remarks/Arguments begin on page 7.**